

Form PTO-1449 U.S. DEPARTMENT OF COMMERCE
(Rev. 2-32) PATENT AND TRADEMARK OFFICEATTY DOCKET NO.
7164.01APPLICATION NO.
09/574,519INFORMATION DISCLOSURE
STATEMENT BY APPLICANT
(use several sheets if necessary)APPLICANT
Eric HendersonFILING DATE
May 18, 2000GROUP ART UNIT
1637

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Examiner Initial	Document Number	Date	Inventor Name	Class	Sub-class	Filing Date (if appropriate)
✓	5,138,174	8/11/1992	Sau Lan Tang	250	492.3	July 16, 1991
↓	5,363,697	11/15/1994	Tohur Nakagawa	73	105	April 29, 1992
↓	5,372,930	12/13/1994	Richard J. Colton et al.	435	6	September 16, 1992
↓	5,666,190	9/9/1997	Calvin F. Quate et al.	355	71	December 4, 1995
↓	5,472,881	12/5/1995	Thomas P. Beebe et al.	436	94	March 21, 1994
↓	5,874,668	2/23/1999	Shaohua Xu et al.	73	105	October 24, 1995
✓	5,985,356	11/16/1999	Peter G. Schultz et al.	427	8	October 18, 1994

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Examiner Initial	Document Number	Date	Country	Class	Sub-class	Translation
✓	WO 99/31267	6/24/1999	PCT	C12Q	1/00	No
↓	WO 00/04382 A1	1/27/2000	PCT	G01N	33/543	No
↓	WO 00/04389	1/27/2000	PCT	G01N	33/53	No
✓	WO 00/04390	1/27/2000	PCT	G01N	33/53	No
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Sheet 2 of 7

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✓	Abstracts of Papers Part I, 214 th "Abstract 027" ACS National Meeting, American Chemical Society, (September 1997) 2pgs
✓	Alves, Carla A. et al., "Atomic Scale Imaging of Alkanethiolate Monolayers at Gold Surfaces with Atomic Force Microscopy", <i>J. Am. Chem. Soc.</i> , Vol. 114, No. 4, (February 12, 1992), 4pgs
✓	Amro, Nabil. A., et al., "Patterning Surfaces Using Tip-Directed Displacement and Self-Assembly", <i>Langmuir</i> , (2000), 16, pgs. 3006-3009
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✓	Bishop, Adeana R., et al., "Self-assembled monolayers: recent developments and applications", <i>Colloid & Interface Science</i> , Vol. 1, No. 1, (February 1996); 6pgs.
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✓	Bottomley, Lawrence A., "Scanning Probe Microscopy", <i>Anal. Chem. Vol. 70, No. 12</i> , (June 15, 1998); pgs. 425R-475R
✓	Carr, D. W., et al., "High-selectivity pattern transfer process for self-assembled monolayer electron beam resists, <i>J. Vac. Sci. Technol. A</i> , 15(3), (May/Jun 1997), pgs. 1446-1450

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<i>AC</i>	Dubois, Lawrence H., et al., "Synthesis, Structure, and Properties of Model Organic Surfaces", <i>Annu. Rev. Phys. Chem.</i> 1992, 43: pgs. 437-463.
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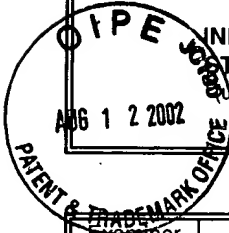
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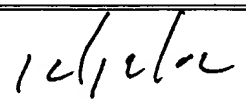
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